

ABSTRACT

Provided are a wafer transfer platform and a wafer transfer method. The wafer transfer platform comprises: a first process robot and a second process robot, for picking, placing, and transferring wafers; a process chamber, including a plurality of reaction chambers arranged at different heights as a first layer and a second layer, the plurality of reaction chambers including first process chambers for performing a first treatment process on the wafers and second process chambers for performing a second treatment process on the wafers, and the plurality of reaction chambers being divided into a first region and a second region in a horizontal direction or a vertical direction; wherein, the first process robot and the second process robot are respectively configured to transfer the wafers in the first region and the second region to transfer the wafers from the first process chambers to the second process chambers.